

APPARATUS FOR TRANSPORTING SUBSTRATES IN AN OVEN**ABSTRACT**

The invention concerns a transport apparatus (4) for transporting substrates (2) in an oven (3). The oven (3) has a channel (9) formed from a floor (10) and two side walls (11, 12) in which the substrates (2) are transported in a transport direction (x'). The floor (10) of the channel (9) has a recess (13) running along
5 one of the side walls (11) for accepting and guiding a rail (14) in transport direction (x'). The rail (14) is set up for accepting at least one substrate (2). A drive mechanism moves the rail (14) in transport direction (x').

(Fig. 1)



G00002



162162